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PATENT & TRADEMARK OFFICE

2822

PATENT
5589-00501/P658

12/C Amdt 9.1603 A.Wood

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of: Xu et al.	§	Group Art Unit: 2822 Examiner: Vockrodt, J.
Serial No. 09/854,177	§	Atty. Dkt. No. 5589-00501 P658
Filed: May 10, 2001	§	
For: METHOD AND SYSTEM FOR DETECTING METAL CONTAMINATION ON A SEMICONDUCTOR WAFER	§	

I hereby certify that this correspondence is being deposited with the U.S. Postal Service with sufficient postage as First Class Mail in an envelope addressed to: **MS: Non-Fee Amendment** Commissioner for Patents, P.O. Box 1450, Alexandria, VA, 22313-1450 on the date indicated below:

September 5, 2003 (Date) — Pamela Gerik (Pamela Gerik)

AMENDMENT; RESPONSE TO OFFICE ACTION MAILED JUNE 5, 2003

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TECHNOLOGY CENTER 2800

MS: Non-Fee Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir/Madam:

This paper is submitted in response to the Office Action mailed June 5, 2003 to further highlight reasons why the application is in condition for allowance.

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks being on page 10 of this paper.